

**Notice of Allowability**

Application No.

10/679,097

Applicant(s)

PUGLIESE ET AL.

Examiner

Art Unit

Raquel Y. Gordon

2853

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to Preliminary Amendment filed 10/3/2003.
2. ☒ The allowed claim(s) is/are 1-28.
3. ☒ The drawings filed on 03 October 2003 are accepted by the Examiner.
4. ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
  - a) ☒ All    b) ☐ Some\*    c) ☐ None    of the:
    1. ☐ Certified copies of the priority documents have been received.
    2. ☒ Certified copies of the priority documents have been received in Application No. 09/772,752.
    3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

\* Certified copies not received: \_\_\_\_\_.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.  
**THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.**

5. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
6. ☐ CORRECTED DRAWINGS ( as "replacement sheets") must be submitted.
  - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review ( PTO-948) attached
    - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date \_\_\_\_\_.
  - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date \_\_\_\_\_.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
7. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

**Attachment(s)**

1. ☐ Notice of References Cited (PTO-892)
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)
3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08),  
Paper No./Mail Date \_\_\_\_\_
4. ☐ Examiner's Comment Regarding Requirement for Deposit  
of Biological Material
5. ☐ Notice of Informal Patent Application (PTO-152)
6. ☐ Interview Summary (PTO-413),  
Paper No./Mail Date \_\_\_\_\_
7. ☐ Examiner's Amendment/Comment
8. ☒ Examiner's Statement of Reasons for Allowance
9. ☐ Other \_\_\_\_\_

### ***Acknowledgment of Receipt of Preliminary Amendment***

The preliminary amendment filed 10/3/2003 had been received and entered.

### ***Reasons for allowance***

The following is a statement of reasons for allowance:

Upon consideration, the inclusion of the claimed substrate and method of forming thereof, as claimed in the combination, is not found in the prior art. This difference is considered patentable over the prior art and reflects an improvement in the field of endeavor since the following apparatus and method claims limitations reflect an improvement in the field of endeavor and over the prior art of record.

The instant application is a divisional of Serial No. 09/772752. With respect to the independent claims, the primary reason for allowance is, the prior art does not recite the claim combination which includes:

A method of forming a slotted substrate, the method comprising: depositing a thin film over a substrate, wherein the thin film contains plural layers including at least an insulating dielectric barrier layer, an interdielectric thin film layer, a resistive layer and a metal conductive layer; forming a slot in the substrate through a slot region that extends through the substrate and the plural layers; and placing the plural layers in a predefined deposit order over the substrate so that a chip count in a shelf surrounding the slot is minimized when the slot is formed in the substrate through the slot region (claim 1);

A method of forming a slotted substrate, the method comprising: depositing at least four plural thin film layers over a substrate, wherein one of the plural thin film layers is a metal thin film layer, one of the thin film layers is an insulating dielectric barrier layer, one of the thin film layers is an interdielectric thin film layer and one of the thin film layers is a resistive layer; and minimizing a chip count in a shelf surrounding a slot defining an area of the slotted substrate by layering the plural thin film layers in a predefined deposit order over the substrate before forming the slot in the substrate through a slot region that extends through the substrate and the plural thin film layers (claim 12);

A method of forming a slot in a substrate comprising: depositing plural thin film layers over a substrate wherein one of the layers is a ductile thin film layer, one of the thin film layers is an insulating dielectric barrier layer, one of the thin film layers is an interdielectric thin film

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layer and one of the thin film layers is a resistive layer; and extending the slot through the ductile thin film layer and the substrate defined by a slot region and layering the plural thin film layers in a predefined deposit order to minimize a chip count in a shelf surrounding the slot. (claim 13);

A coated substrate for a center feed printhead comprising: means for depositing at least four plural thin film layers over a substrate, wherein one of the plural thin film layers is a metal thin film layer, one of the thin film layers is an insulating dielectric barrier layer, one of the thin film layers is an interdielectric thin film layer and one of the thin film layers is a resistive layer; means for forming the slot in a substrate through a slot region that extends through the substrate and thin film; and means for minimizing a chip count in a shelf surrounding a slot defining an area of the slotted substrate by layering the plural thin film layers in a predefined deposit order over the substrate before forming the slot in the substrate through a slot region that extends through the substrate and the plural thin film layers (claim 20);

A coated substrate for a center feed printhead comprising: a substrate; a thin film applied over the substrate, wherein the thin film contains plural layers including at least an insulating dielectric barrier layer; interdielectric thin film layer, a resistive layer and a metal conductive layer; and a slot region extending through the substrate and the thin film, that a chip count in a shelf surrounding the slot region is minimized when a slot is formed in the substrate through the slot region (claim 21).

The instant application is a divisional of Serial No. 09/772752, filed 9/21/2001, now Patent No. 6648732. An involuntary restriction requirement precludes Patent No. 6648732 from being applied as a prior art teaching.

Further, an exhaustive search has revealed no prior art to disprove novelty or non-obviousness of the claimed invention.

Hence, the independent claim is now deemed to be allowable. The dependent claims are allowable since they depend from allowed base claims.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

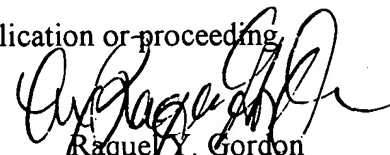
#### **Contact Information**

Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Raquel Y. Gordon, whose telephone number is (571) 272-2145. The Examiner can normally be reached on M-F 8:30-5:00.

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If attempts to reach the examiner by telephone are unsuccessful, the Examiner's supervisor, Stephen Meier can be reached on (571) 272-2149. A fax number is available upon request.

Any inquiry of a general nature or relating to the status of this application or proceeding may be directed to the Examiner or Supervisor.

  
Raquel Y. Gordon  
Primary Examiner  
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October 8, 2004